

In the claims

Please AMEND claim 1, CANCEL claims 10 and 19-59 without prejudice, and ADD new claims 60-70 so that the claims to read as follows:

1. (Currently Amended) A semiconductor die comprising:
 - a substrate device level comprising substrate transistors, the substrate transistors having a substrate pitch, some portion of each of the substrate transistors formed in a monocrystalline substrate; ~~and~~
 - a first above-substrate device level formed above the substrate device level, the first above-substrate device level comprising first above-substrate devices having a first above-substrate pitch, wherein the first above-substrate pitch is smaller than the substrate pitch; and
 - a second above-substrate device level formed over the first above-substrate device level, the second above-substrate device level having a second above-substrate pitch, wherein the second above-substrate pitch is smaller than the substrate pitch.

2. (Previously presented) The semiconductor die of claim 1 wherein the first above-substrate devices of the first above-substrate device level comprises a first plurality of memory cells, the memory cells at the first above-substrate pitch.

3. (Previously presented) The semiconductor die of claim 2 wherein the substrate transistors of the substrate device level comprises driver circuitry.

4. (Previously presented) The semiconductor die of claim 3 wherein the first above-substrate device level comprises:
a first area, said first area comprising portions of the first plurality of memory cells, the memory cells having the first above-substrate pitch; and
a second area, said second area having a fan-out pitch, wherein said fan-out pitch is larger than the first above-substrate pitch.
5. (Original) The semiconductor die of claim 4 wherein the first area comprises a plurality of substantially parallel, substantially coplanar rails.
6. (Original) The semiconductor die of claim 5 wherein photolithography processes are optimized to minimize the first above-substrate pitch of the plurality of rails in the first area.
7. (Original) The semiconductor die of claim 6 wherein the plurality of rails is patterned using off-axis illumination.
8. (Original) The semiconductor die of claim 7 wherein the plurality of rails is patterned using a dipole illumination aperture.
9. (Canceled)
10. (Canceled)
11. (Original) The semiconductor die of claim 5 wherein the rails comprise a first plurality of memory lines

electrically connected to a first plurality of vertical interconnects at a first end and a second plurality of memory lines electrically connected to a second plurality of vertical interconnects at a second end opposite the first end, the first and second pluralities interleaved.

- 12.(Original) The semiconductor die of claim 2 wherein the plurality of memory cells form part of a monolithic three dimensional memory array.
- 13.(Original) The semiconductor die of claim 12 wherein the memory array comprises segmented bit lines and global bit lines, wherein two segmented bit lines share a vertical connection to an associated global bit line.
- 14.(Canceled)
- 15.(Original) The semiconductor die of claim 2 wherein the memory cells are passive element memory cells.
- 16.(Previously presented) The semiconductor die of claim 15 wherein the memory cells are antifuse-diode cells.
- 17.(Original) The semiconductor die of claim 2 wherein the memory cells are thin film transistors having a charge-storage dielectric.
- 18.(Original) The semiconductor die of claim 17 wherein the memory cells are arranged in series-connected NAND strings.
19. (Canceled)

20. (Canceled)

21. (Canceled)

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50. (Canceled)

51. (Canceled)

52.(Canceled)

53.(Canceled)

54.(Canceled)

55.(Canceled)

56.(Canceled)

57.(Canceled)

58.(Canceled)

59.(Canceled)

60.(New) A semiconductor die comprising:

- a substrate device level comprising substrate transistors, the substrate transistors having a substrate pitch, some portion of each of the substrate transistors formed in a monocrystalline substrate, wherein the substrate transistors of the substrate device level comprise driver circuitry; and
- a first above-substrate device level formed above the substrate device level, the first above-substrate device level comprising first above-substrate devices having a first above-substrate pitch, wherein the first above-substrate pitch is smaller than the substrate pitch, wherein the first above-substrate device level comprises:
 - a first plurality of memory cells, the memory cells at the first above-substrate pitch;

a first area, said first area comprising:
portions of the first plurality of memory cells, the memory cells having the first above-substrate pitch; and
a plurality of substantially parallel, substantially coplanar rails, wherein the rails comprise a first plurality of memory lines electrically connected to a first plurality of vertical interconnects at a first end and a second plurality of memory lines electrically connected to a second plurality of vertical interconnects at a second end opposite the first end, the first and second pluralities interleaved; and
a second area, said second area having a fan-out pitch, wherein said fan-out pitch is larger than the first above-substrate pitch.

- 61.(New) The semiconductor die of claim 60 wherein photolithography processes are optimized to minimize the first above-substrate pitch of the plurality of rails in the first area.
- 62.(New) The semiconductor die of claim 61 wherein the plurality of rails is patterned using off-axis illumination.
- 63.(New) The semiconductor die of claim 62 wherein the plurality of rails is patterned using a dipole illumination aperture.
- 64.(New) The semiconductor die of claim 60 further comprising a second above-substrate device level formed over the first above-substrate device level, the second above-substrate

device level having a second above-substrate pitch, wherein the second above-substrate pitch is smaller than the substrate pitch.

- 65.(New) The semiconductor die of claim 60 wherein the plurality of memory cells form part of a monolithic three dimensional memory array.
- 66.(New) The semiconductor die of claim 65 wherein the memory array comprises segmented bit lines and global bit lines, wherein two segmented bit lines share a vertical connection to an associated global bit line.
- 67.(New) The semiconductor die of claim 60 wherein the memory cells are passive element memory cells.
- 68.(New) The semiconductor die of claim 67 wherein the memory cells are antifuse-diode cells.
- 69.(New) The semiconductor die of claim 60 wherein the memory cells are thin film transistors having a charge-storage dielectric.
- 70.(New) The semiconductor die of claim 69 wherein the memory cells are arranged in series-connected NAND strings.